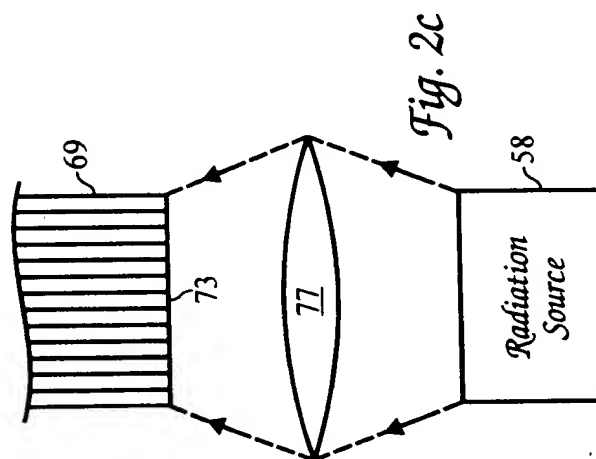
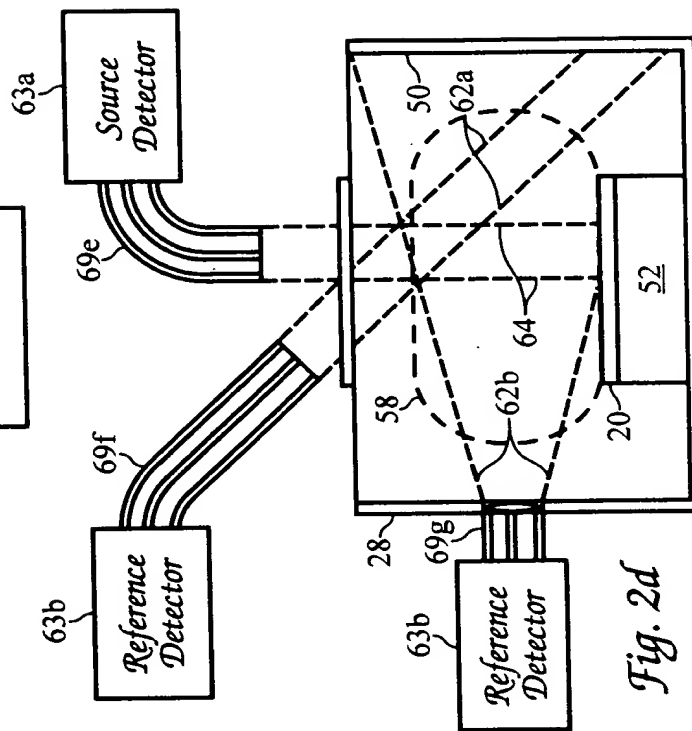
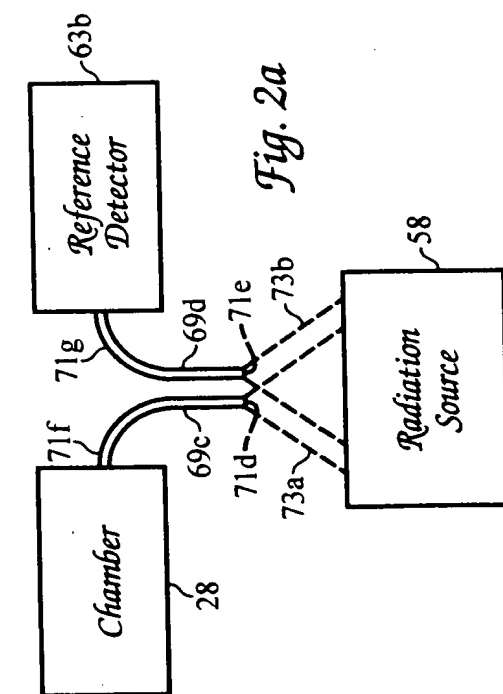
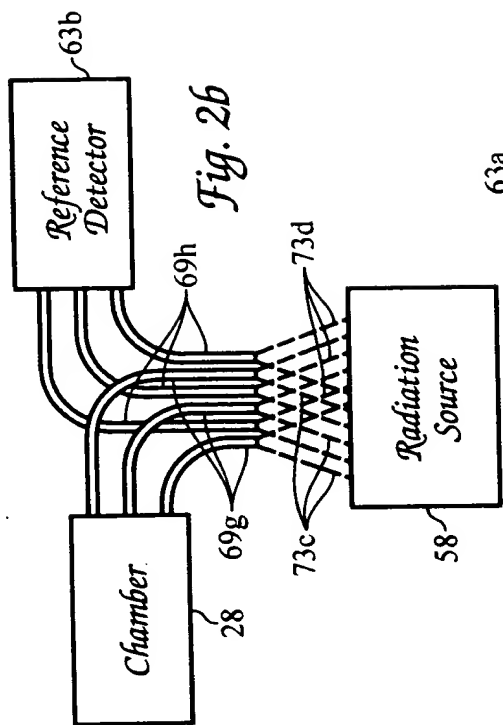


Fig. 1

604280" E3464659



Measure Signals  
Before Processing  
 $\chi_0, \gamma_0$

Ignite Plasma

Measure Sample  
Signal  $\chi_1$

Calculate Correction  
Factor  $C$

Monitor Sample and  
Reference Signals  
 $\chi_+, \gamma_+$

Calculate Normalized  
Signal  $\chi_{nt}$

Evaluate  $\chi_{nt}$  ;  
Reach Desired  
Value or Pattern?

Stop Etch

no

Yes

Fig. 3

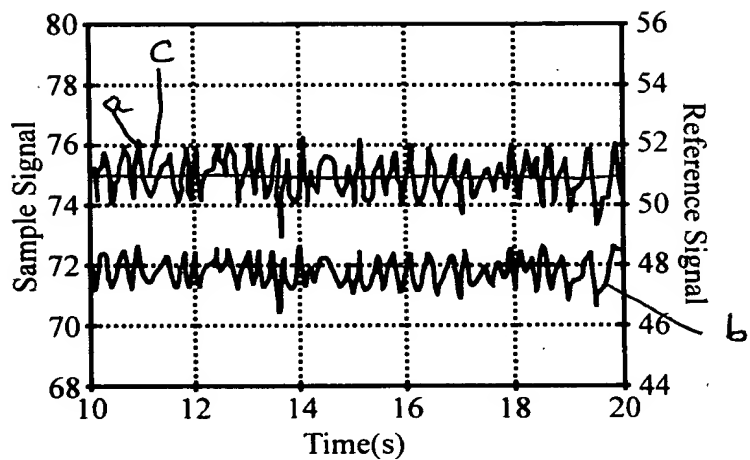


Fig. 4

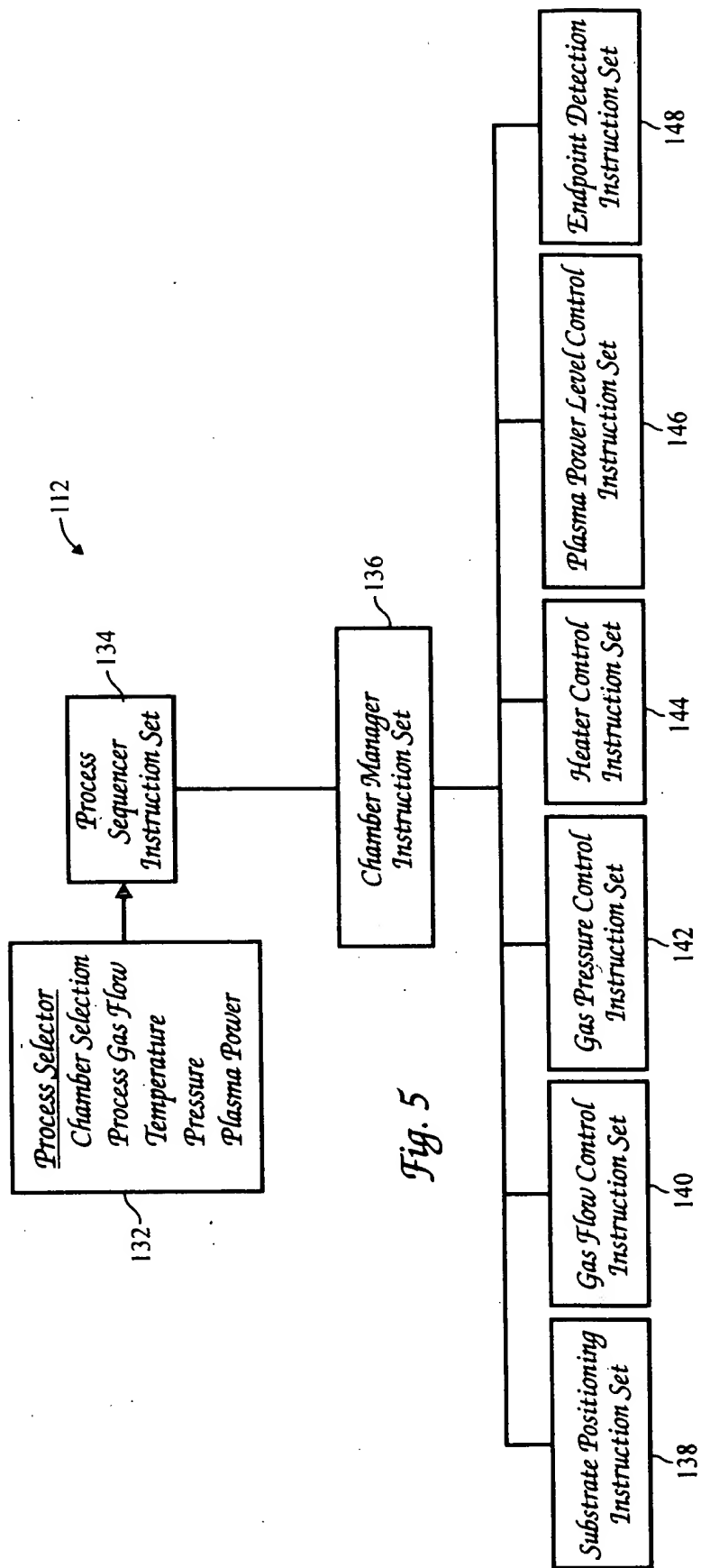


Fig. 5

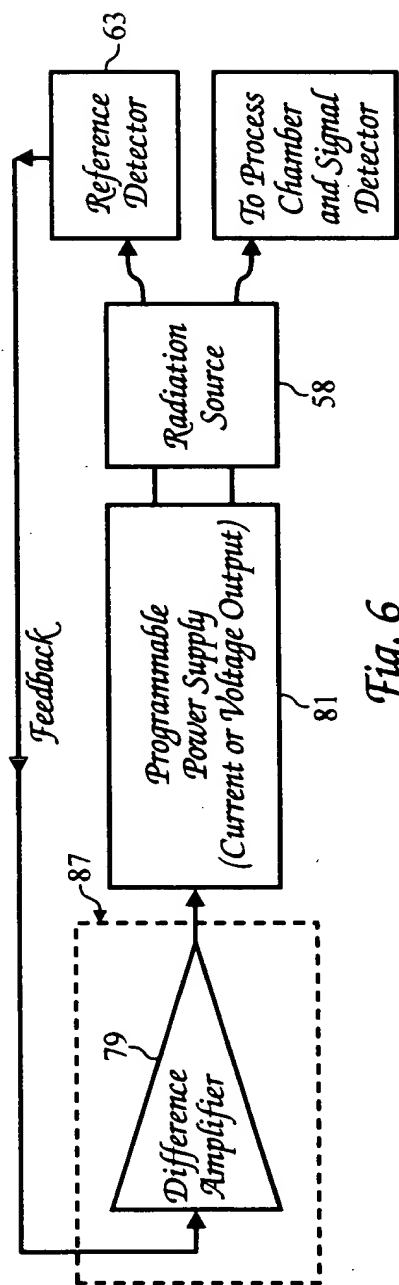


Fig. 6

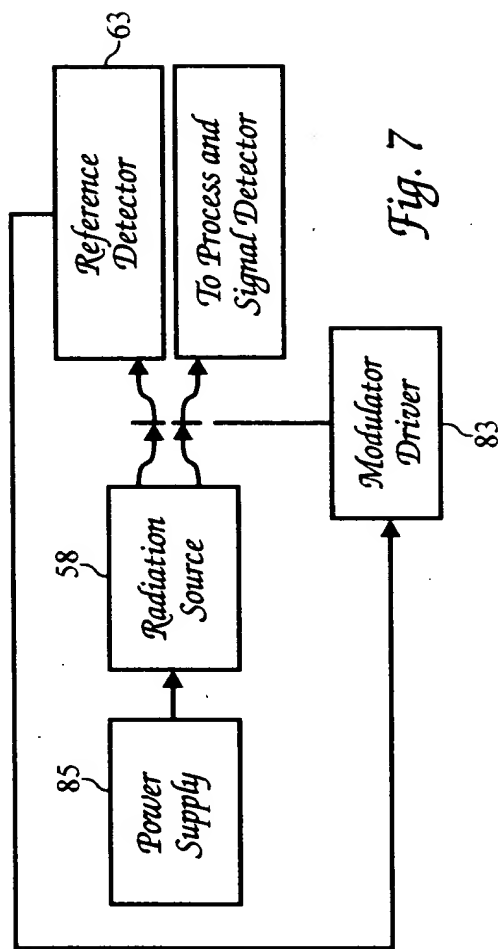


Fig. 7